



Photoemission Electron Microscope for the Russian-German Laboratory



FOCUS PEEMPhoto Emission Electron Microscope







Integrated sample stage





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Retarding imaging energy filter



G. Schönhense, J. Phys.: Condens. Matter 11, 9517 (1999)

FOCUS PEEMPhoto Emission Electron Microscope





Various contrast mechanisms:

- work function ۰
- topographic
- chemical
- magnetic



30 nm lateral resolution



Spectromicroscopy || Microspectroscopy |

k-space imaging

Microscopy



Microspectroscopy

XAS with lateral resolution



Spectromicroscopy

Ag-covered/Si-grid

Chemical contrast





Spectromicroscopy

 $FoV = 9 \mu m$

Ni-rods in SiO₂

Chemical contrast by Oxygen

hv=537.6 eV (Max Oxygen absorption)





hv=853 eV (Max Ni absorption)





k-space imaging

Angle-resolved photoemission from Graphene: scanning the entire Brillouin zone



Micro-XPS

Plot 5

70.5 71

70





Monitoring of surface processes during deposition/intercalation/oxidation etc.

Graphene/Ir(111) Gr/Bi/Ir(111) Bi/Gr/Bi/Ir(111) F0Y-20 µm F0Y-20 µm F0Y-20 µm

(measured offline using Hg-lamp)

Workfunction cut-off spectra



(measured offline using Hg-lamp)

- Microscopy and Micro-XPS/XAS/Workfunction analysis.
- Possibility of in-vacuum sample transfer to/from RGBL-1.
- Hg-lamp (offline) and synchrotron beam.

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